

INFORMATION DISCLOSURE CITATION <i>(Use several sheets if necessary)</i>	Docket Number (Optional) TWI-8570	Application Number NEW
	Applicant(s) Michial Duff Howell et al.	
	Filing Date HEREWITH	Group Art Unit Unknown

U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	REF	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE
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							YES	NO
Jf	*AQ	4-357836	06/04/1991	Japan (translation included)	H01L	21/304	X	
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Jf	*AY	K. Imen, S.J. Lee & S.D. Allen, "Laser-assisted micron scale particle removal," <i>Appl. Phys. Lett.</i> , Vol 58, No. 2, 14 January 1991, pp. 203-205.
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Examiner <i>Shauntina Suga</i>	Date Considered 5/2/04
Examiner: Initial if citation considered, whether or not citation is in conformance with MPEP Section 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.	